

Semitool 4600 L Spin Rinser Dryer

The Semitool Model 4600L is the industry choice for low volume, high reliability rinsing and drying of large area substrates up to 380 mm square.

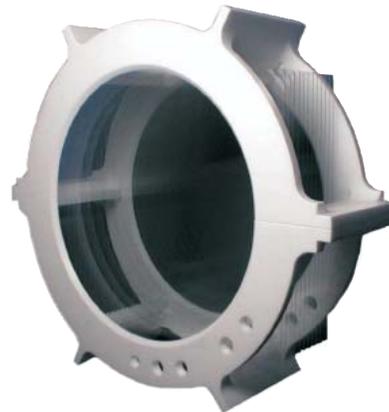
With its small footprint and ease-of-use, the 4600L is ideal for flat panel display manufacturing or other applications requiring the wet processing of large area substrates.

The Semitool 4600L utilizes an electropolished stainless steel process chamber which supports a full DI water spin-rinse cycle, followed by a hot N₂ spin-dry cycle. The tool includes:

- **Twin DI Water Rinse Manifolds** –
assuring full coverage of substrates during DI rinse
- **On-board N₂ Heater & Point of Use N₂ Filter** –
minimizing particles
- **CY-20 Anti-static Cell** –
reducing static charge on the process carrier and wafers
- **RM-20 Resistivity Monitor** –
enabling "rinse to clean" process recipes
- **WR-20B Water Recirculation** –
minimizing organic build-up in DI water lines
- **PSC-102 Controller** –
programming and storing multiple process recipes
- **Carrier Present Sensor** –
preventing operation of an unloaded tool



Optional clamshell shown with 380 mm square substrates



The Semitool 4600L is a complete process solution.

With an optional Clamshell Carrier (see photo above), substrates are fully protected throughout the entire spin rinse dry process. The Clamshell Carrier also provides more uniform DI and N₂ coverage of the substrates to optimize rinsing and promote rapid, water-spot free spin drying.

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Throughput, Performance & Reliability

With a proven design and minimal facility requirements, the Semitool 4600L delivers superior operating results:

- Throughput: Typically 50-60 substrates an hour¹
- Uptime: > 95%
- Footprint: 40.3" W x 43.1" L x 71" H
- Substrate Size: Up to 380 mm square

Standard Features and Options

One Year Parts and Labor Warranty
EPO Emergency Off Switch
Earthquake Tiedowns
Auto Door
Six Bolt Rotor for Customer Carrier or Semitool Clamshell
Manual on Clean Room Paper (option)
Installation (option)
CE Certification (option)

Facility Requirements

DI Water: 30 to 35 psi; 3.5 to 4.6 GPM
Nitrogen: 30 to 40 psi; 8.0 to 10.0 CFM
Exhaust: 7 CFM
Drain: 1.5 inch PVC Drain Box Fitting
Electrical: Standard: 208 VAC, 3 phase, 20 amp²

Dual DI water rinse manifolds assure full coverage of wafers during DI rinse. The chamber is built of electropolished 316 stainless steel for maximum contamination control.



¹ Dependent on process time.
² Voltage and current varies with country,
Three phase power required, consult factory for specifics.

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